Notice of Allowability	Application No.	Applicant(s)	
	10/708,593	IZUMI ET AL.	
	Examiner	Art Unit	
	Michelle Estrada	2823	
The MAILING DATE of this communication apperall claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in or other appropriate community GHTS. This application is s	this application. If not included nication will be mailed in due course.	
1. This communication is responsive to <u>2/7/05</u> .			
2. The allowed claim(s) is/are <u>1-6</u> .			
3. The drawings filed on 12 March 2004 are accepted by the l	Examiner.		
<ul> <li>4.</li></ul>			
Attachment(s)  1. ☑ Notice of References Cited (PTO-892)  2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)	<u> </u>	ormal Patent Application (PTO-152) mmary (PTO-413),	
3. Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date	Paper No./I	Mail Date Amendment/Comment	
4. Examiner's Comment Regarding Requirement for Deposit	8. 🛛 Examiner's	Statement of Reasons for Allowance	
of Biological Material	9.  Other	·	

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

The application has been amended as follows:

Cancel claims 7-15.

Election/Restrictions

This application is in condition for allowance except for the presence of claims 7-15 to an invention non-elected without traverse. Accordingly, claims 7-15 been cancelled.

Allowable Subject Matter

Claims 1-6 are allowed.

The following is an examiner's statement of reasons for allowance: there is no disclosure in the prior art of irradiating the surface silicon layer of the SOI substrate with infrared rays while supplying a mixed gas of hydrogen gas and hydrocarbon gas into the film formation chamber, and metamorphosing the surface silicon layer into a single crystal silicon carbide thin film.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably

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accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Michelle Estrada whose telephone number is 571-272-1858. The examiner can normally be reached on Monday through Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri can be reached on 571-272-1855. The fax phone numbers for the organization where this application or proceeding is assigned are 571-273-0224 for regular communications and 703-308-7724 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 571-272-2800.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

George Fourson Primary Examiner Art Unit 2823

MEstrada April 1, 2005